in Gy 1763



35.C11969 REI

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Reissue Application of: Previous

Examiner: L. Alejandro

NOBUMASA SUZUKI

Appln. No.: 09/657,971

Filed: September 8, 2000

Patent No.: 5,803,975

Issued: September 8, 1998

For: MICROWAVE PLASMA

PROCESSING APPARATUS
AND METHOD THEREFOR

October 11, 2000

BOX REISSUE

Commissioner for Patents Washington, D.C. 20231

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the document listed on the enclosed Form PTO-1449. A copy of the listed document is also enclosed.

The enclosed document is a certified translation of JP-90591. A non-certified copy of this document was previously provided with the Information Disclosure Statement dated September 7, 2000.

CONCLUSION It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered. Applicant's undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our address given below. Respectfully submitted, orney for Applicant Registration No. 9,767FITZPATRICK, CELLA, HARPER & SCINTO 30 Rockefeller Plaza New York, New York 10112-3801 Facsimile: (212) 218-2200 109853v1 - 2 -